



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney Docket No. 016778/0437

Applicant: Yukio MORISHIGE et al.

Title: METHOD AND DEVICE FOR CORRECTING PATTERN
FILM ON A SEMICONDUCTOR SUBSTRATE

Application No.: 09/981,712

Filing Date: October 19, 2001

Examiner: Fuller, Eric B.

Art Unit: 1762

**AMENDMENT AND REPLY TO RESTRICTION REQUIREMENT,
WITH TRAVERSE**

Mail Stop NON-FEE AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

This communication is responsive to the Non-Final Office Action dated October 2, 2003, concerning the above-referenced patent application.

Restriction Election is provided on page 2 of this document.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this document.

Remarks/Arguments begin on page 6 of this document.

Please amend the application as follows:

Restriction Election:

Applicants elect Group II, claims 6-12, with traverse. Claim 6 has been amended to remove the "gas circulatory unit" feature, and thus it is submitted that the features recited in presently pending independent claim 6 are very similar to the features recited in originally-filed independent claim 1. Claims 11 and 12 have also been amended based on the amendments made to claim 6.

Accordingly, claims 1-12 should all be examined by the Examiner. In particular, the Office Action asserted that "a different apparatus, such as one that does not require a gas circulatory unit, may perform the method as claimed." This assertion is no longer valid based on the amendments made to claim 6.